



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 1632
Norio KIMURA et al. : Attorney Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Jeffrie R. Lund
SUBSTRATE POLISHING APPARATUS : MAIL STOP: AF
AND SUBSTRATE POLISHING METHOD

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**RESPONSE UNDER 37.CFR1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1700**

Sir:

In response to the Office Action of May 3, 2006, the period for response to which having been extended by two months to October 3, 2006, kindly amend the above-referenced U.S. patent application as follows:

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO BE DEPOSITED
ACCOUNT NO. 22-8975